



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Confirmation No. 7353**
Tetsuji TOGAWA et al. : Attorney Docket No. 2005_1890A
Serial No. 10/559,135 : Group Art Unit 3723
Filed February 11, 2008 : Examiner Eileen P. Morgan

SUBSTRATE POLISHING
APPARATUS AND SUBSTRATE
POLISHING METHOD : **Mail Stop: Amendment**

AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

THE COMMISSIONER IS AUTHORIZED
TO CHARGE ANY DEFICIENCY IN THE
FEES FOR THIS PAPER TO DEPOSIT
ACCOUNT NO. 23-0975

Sir:

In response to the Office Action of November 12, 2008, the period for response having been extended by one month to March 12, 2009, please amend the above-identified U.S. Patent application as follows.